

Form PTO-159

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APPLICANT Gurtej S. Sandhu

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2823

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA					
	AB					
	AC					
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	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM						
	AN						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

AO	J. Aarik, et al, Control of Thin Film Structure by Reactant Pressure in Atomic Layer Deposition of TiO ₂ , Journal of Crystal Growth Vol. 169, (1996), pgs. 496-502.
AP	
AQ	
AR	

EXAMINER *Michael D. O'Neil* DATE CONSIDERED *12/23/02*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.